

High-Performance UHP Gas Analyzers and Integrated Systems



Electronic Gas

Capabilities:

- Continuous trace impurity monitoring in electronic bulk gases
- All critical measurements covered using laser-based Cavity Ring-Down Spectroscopy (CRDS) and Atmospheric Pressure Ionization Mass Spectrometry (APIMS) technologies
- Eliminates batch sampling and long analysis times typical for legacy analytical methods

NEW



Atmospheric Pressure Ionization Mass Spectrometers for Real-Time, ppt-Level, Multi-Impurity Analysis
VeraSpec™ APIMS



CRDS for ppt-Level H₂O, CH₄, and NH₃
HALO KA Max™



CRDS for Pre-Purifier Measurement for H₂O, CH₄, CO, CO₂, and C₂H₂
Spark™



CRDS Trace Gas Analyzer for O₂
HALO OK™



ppt-Level CRDS for CO and CO₂
HALO Max QCL™



Specialty Gas

Capabilities:

- Trace H₂O analysis in UHP ammonia for HB LED production
- Quality monitoring for process specialty gases, including HCl, Cl₂, CO₂, N₂O, NF₃, C_xF_y, Xe, and more
- Dynamic gas blending monitoring
- Corrosion-resistant analyzers available



Real-Time, Multi-Stream Process NIR Spectrometer
NIR-O™



Mass spectrometer for pure & blended specialty gases
MAX300-LG™



CRDS for Corrosive, Rare, and Fluorinated Gases
HALO 3 / KA™



CRDS for single-digit ppb level H₂O in NH₃
ALOHA+ H₂O™



Process Tools

Capabilities:

- Tool monitoring for trace H₂O, O₂ and HF
- Low pressure, low temperature EPI, ALD, MOCVD process monitoring
- Real-time moisture measurement in load lock, transfer, and process chambers



Aluminum Oxide Dew Point Meters for Portable/Fixed/Loop-Powered Applications
XDT™ / XPDM™ / LPDT™ / LPDT2™



Mass Spectrometer for Real-Time, ppb-Level Analysis
MAX300-LG™



CRDS Trace-Level, Low-Pressure Moisture Analyzer
HALO QRP™



Electrochemical / ZrO₂ analyzers for trace O₂
AOI 3520/ZrO₂000



Airborne Molecular Contaminants

Capabilities:

- Continuous AMC monitoring for ambient HCl, HF, and NH₃ in semiconductor clean rooms
- FOUP Monitoring Tools, Reticle Nests, Process & Sub-Fab Environments
- Mobile & stationary integrated solutions



CRDS Analyzers for Monitoring ppt-Level HCl, NH₃, and HF in Clean Room Air
T-I Max™ HCl | T-I Max™ NH₃ | T-I Max™ HF



Mobile Solution for AMC Monitoring
GO-Cart™



Trace HCl, NH₃, and HF Analyzer for Continuous AMC Monitoring
T-I Max X3™ AMC Monitoring Solution

NEW



AMC Stationary Sampling System
Multi-Max™
AMC Monitoring Solution



Life Safety

Capabilities:

- Air monitoring
- O₂ deficiency and toxic chemicals
- Worker safety
- Early detection of chemical releases



Trace to Percent Oxygen Monitors for Portable and Fixed Applications
Series 1300™ and **OXY-SEN™**



Powerful Quadrupole Mass Spectrometer for Toxic Gas Ambient Air Monitoring
MAX300-TGM™



Systems Integration

Capabilities:

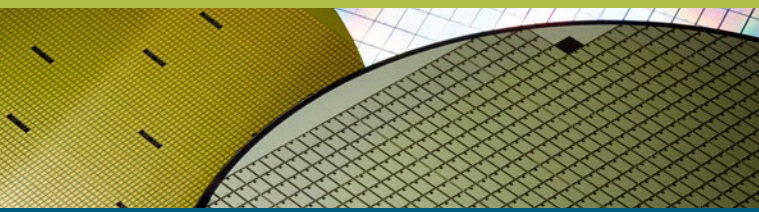
- Real-time monitoring of all critical impurities in a single integrated solution for N₂, Ar, He, H₂, O₂ and xCDA
- Gas cycling options - monitor all gases in a single system
- Bulk gas and AMC monitoring



Mass spectrometer for continuous, ppt-level impurity analysis
VeraSpec™ APIMS



Total solution for gas analysis - dedicated or gas-cycling options
QC / IQC Cabinet



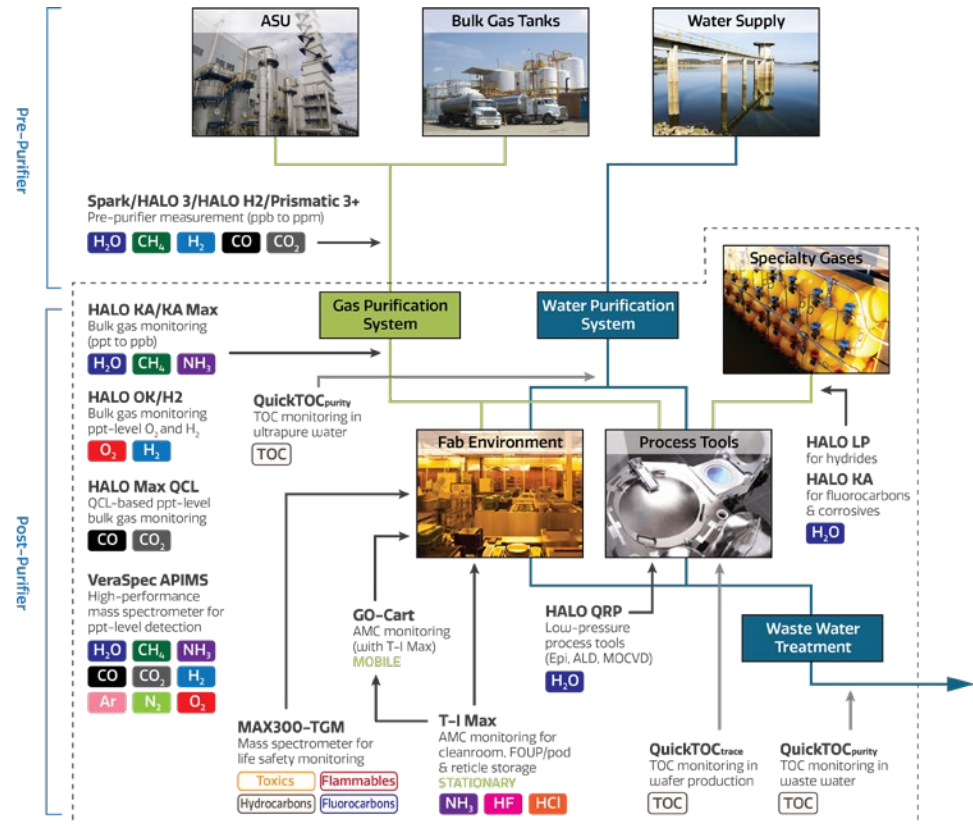
Chemical Analysis for Blending and Wafer Cleaning

- Measure gases & liquids composition, metals contamination
- Continuous online measurement in seconds
- Extractive or inline sample probes
- Multichannel - One instrument can measure up to 12 process streams
- Compatible with corrosive and toxic samples
- Low consumables & low maintenance

Optical Absorption Spectrometer for gas & liquid monitoring
NIR-O / ClearView® DB



Total Solutions for the Semiconductor Industry



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